

Amendments to the Claims:

This listing of claims will replace all prior listings of claims in the application.

Listing Of Claims:

Claim 1 (currently amended): A load-lock system comprising:
a load-lock chamber arranged between a storage port which stores a substrate and a process chamber which processes the substrate in a process space maintained at a pressure lower than a pressure in the outside; and
a dehumidifying unit which supplies dehumidified gas into said load-lock chamber ~~forms a dehumidified environment in said load-lock chamber~~.

Claim 2 (original): A system according to claim 1, wherein said dehumidifying unit has a controller which controls a humidity in said load-lock chamber so as to prevent moisture in said load-lock chamber from condensing when a temperature in said load-lock chamber drops.

Claim 3 (original): A system according to claim 1, wherein said dehumidifying unit has a pipe which communicates with said load-lock chamber, a cooler and a heater placed in the pipe, and a controller separately controls the cooler and heater.

Claim 4 (original): A system according to claim 3, wherein said dehumidifying unit has a filter for removing moisture, the filter being arranged between the cooler and the heater in the pipe.

Claim 5 (currently amended): A load-lock system ~~according to claim 1,~~
~~further comprising another~~

a load-lock chamber arranged between a storage port which stores a substrate and a process chamber which processes the substrate in a process space maintained at a pressure lower than a pressure in the outside

a machine chamber arranged between said storage port and said load-lock chamber,

~~wherein said~~ a dehumidifying unit which supplies dehumidified gas dehumidifies into said ~~another~~ machine chamber.

Claim 6 (currently amended): A system according to claim 5, wherein said dehumidifying unit has a controller which controls a humidity in said ~~another~~ machine chamber so as to prevent moisture in said load-lock chamber from condensing when a temperature in said load-lock chamber drops.

Claim 7 (currently amended): A system according to claim 6, wherein the controller calculates a humidity in said load-lock chamber and the humidity in said ~~another~~ machine chamber, and said dehumidifying unit controls the humidity in said ~~another~~ machine chamber so as to prevent moisture in gas flowing from said ~~another~~ machine chamber into said load-lock chamber from condensing when the temperature in said load-lock chamber drops, on the basis of a calculation result by the controller.

Claim 8 (currently amended): A system according to claim 5, wherein said dehumidifying unit has a pipe which communicates with said ~~another~~ machine

chamber, a cooler and a heater placed in the pipe, and a controller separately controls the cooler and heater.

Claim 9 (currently amended): A system according to claim 5, further comprising a static eliminator which eliminates static electricity in said ~~another~~ machine chamber.

Claim 10 (currently amended): A system according to claim 5, wherein said ~~another~~ machine chamber includes a transport portion which transports the substrate between said storage port and said load-lock chamber.

Claim 11 (currently amended): An exposure processing system comprising:

a storage port which stores a substrate; an exposure processing unit which exposures the substrate in a process space maintained at a pressure lower than a pressure in the outside;

a load-lock chamber arranged between said storage port and said exposure processing unit; and

a dehumidifying unit which ~~forms a dehumidified environment in~~ supplies dehumidified gas into said load-lock chamber.

Claim 12 (canceled).

Claim 13 (currently amended): ~~[[A]]~~ An exposure processing system according to claim 11, further comprising:

a storage port which stores a substrate;

an exposure processing unit which exposes the substrate in a process
space maintained at a pressure lower than a pressure in the outside;

a load-lock chamber arranged between said storage port and said exposure
processing unit;

a mini-environment arranged between said storage port and said load-lock
chamber,

~~wherein said~~ a dehumidifying unit which supplies dehumidified gas into
said mini-environment.

Claim 14 (original): A device manufacturing method comprising:
an exposure step of exposing a substrate using an exposure processing
system as defined in claim 11; and
a development step of developing the exposed substrate.

Claim 15 (new): A device manufacturing method comprising:
an exposure step of exposing a substrate using an exposure processing
system as defined in claim 13; and
a development step of developing the exposed substrate.